In The Claims:

Claim 1. (currently amended) A dynamic mask module adapted to transfer a mask pattern to a photo-resist on a substrate, the dynamic mask module comprising:

a microcomputer system;

a ~~mask pattern generator~~ digital light processing optical projector disposed over the substrate and electrically connected to the microcomputer system, wherein the microcomputer system transmits an image signal of the mask pattern to the ~~mask pattern generator~~ digital light processing optical projector for generating pluralities of opaque areas and transparent areas and outputting the mask pattern; and

a light source disposed over the ~~mask pattern generator~~ digital light processing optical projector, light of the light source projecting on the opaque areas and transparent areas for transferring the mask pattern to the photo-resist.

Claim 2. (currently amended) The dynamic mask module of claim 1, further comprising a focusing lens disposed between the ~~mask pattern generator~~ digital light processing optical projector and the substrate adapted to minify or magnify the mask pattern.

Claims 3-10. (cancelled)

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